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(71)Applicant : TOKYO ELECTRON LTD  
TOKYO ELECTRON TOHOKU LTD

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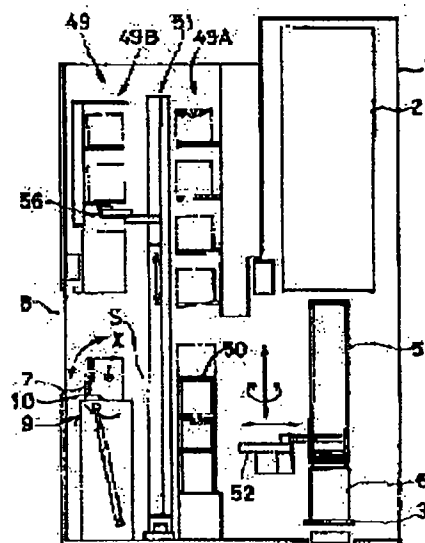
(72)Inventor : OSAWA SATORU  
IWAI HIROYUKI  
KIKUCHI HISASHI

## (54) METHOD AND EQUIPMENT FOR PROCESSING

### (57)Abstract:

**PURPOSE:** To provide a method and an equipment for processing in which the processing capacity can be enhanced while reducing the size of the equipment.

**CONSTITUTION:** A mechanism 9 for rotating a carrier 7 housing a plurality of objects to be processed vertically around a center of rotation X within its side face region and converting the objects from vertical attitude to horizontal attitude is disposed at the carry-in/carry-out port 8 of a processing chamber 1 housing a vertical heat treatment furnace 2. A section 49 for housing a plurality of carriers 7 is disposed above the attitude converting mechanism 9 and the carrier 7 is carried between the housing section 49 and the mechanism 9 and the heat treatment furnace 2 by means of a carrying mechanism 51. The object to be processed is transferred, by means of a transfer mechanism 52, between the carrier 7 carried to the heat treatment furnace 2 and an object holder 5 being carried into the furnace 2 or carried out of the furnace 2.



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